

# Postdoctoral Position in Plasma Processing Science

## University of Houston

We have an experimental postdoctoral position available, starting immediately. The funded project involves plasma etching studies and will be very fundamental in nature, producing publications that will address etching mechanisms in microelectronics fabrication. Several optical spectroscopies, surface analysis, and laser-based diagnostic techniques will be employed to study both plasma chemistry and plasma-surface interactions. Candidates interested in academic research are particularly encouraged. Candidates for this position must have a Ph.D. (or equivalent) degree in Engineering, Physics, or Chemistry. Experience with plasma diagnostics is highly desired. The starting salary will be commensurate with experience and qualifications. Applicants should contact Vincent M. Donnelly ([vmdonnelly@uh.edu](mailto:vmdonnelly@uh.edu)).